



JPW

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Hou, Chien-Chou; et al.)	Examiner:	Deo, Duy Vu Nguyen
)		
Serial No.:	10/600,377)	Art Unit:	1765
)		
Filed:	June 20, 2003)	Our Ref:	B-5130 621033-6
)		
For:	"METHOD OF ETCHING UNIFORM SILICON LAYER")	Date:	April 11, 2006
)		
)	Re:	<i>Response</i>
)		

RESPONSE

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This is in reply to the non-final Office Action mailed on January 11, 2006, a response to which is due no later than

April 11, 2006.

Please consider the following remarks. All remarks herein are made without prejudice

Remarks/Arguments begin on Page 2 of this Response.